



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Kiyoshi MOTEKI &  
Satoru OSHIKAWA

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ORIGINALLY FILED

U.S. Application No. 09/856,384

Filing Date: May 21, 2001

For: Optical Apparatus, Exposure Apparatus,  
Laser Light Source, Gas Supply Method,  
Exposure Method, and Device Manufacturing  
Method

GAU: 2851

Examiner:

Atty. Docket No. 25,096-USA

Commissioner for Patents  
Washington, D.C. 20231

**SECOND PRELIMINARY AMENDMENT**

Sir:

Please amend the application as set forth below.

**In The Specification**

On page 1, please delete the title and replace it with the following:

--Optical Apparatus, Exposure Apparatus, Laser Light Source, Gas Supply  
Method, Exposure Method, and Device Manufacturing Method--.

Respectfully submitted,

  
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GAH:mdb

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